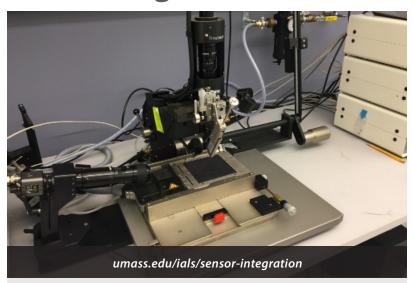
Sensor Integration



Located on the 4th floor in the Life Science Laboratories the Sensor Integration facility has equipment for precise integration of optical and electronic components into compact systems. Equipment includes probe station with laser cutter, wafer saw, wire bonders, a flip chip bonder, via plating, and a laser PCB prototyping tool.

We offer training to users to conduct experimentation for use on a fee for service basis to both internal and external researchers, academic or industry based. Following an initial consultation, covering experimental parameters training and access is arranged through the director.

ACCESS

To request access, training, or additional information please contact Joseph Bardin at jbardin@ umass.edu or Robert Jackson at jackson@ecs.umass.edu.

Our rates are competitive and tiered based on needs and usage. Visit our website at umass.edu/ *ials/sensor-integration* for current listing.

TRAINING

Training for new users consists of:

- · lab safety training,
- operation of the instrument and associated software.
- use of data analysis software,
- · exporting or presenting data,
- clean up and shutdown of the instrumentation.

Once the training is complete, researchers may schedule their experiments through the directors of Sensor Integratioin (Joseph Bardin or Robert Jackson) or online through FOM (Facilities Online Manager) at fom.umass.edu/fom

UMassAmherst | Core Facilities

Institute for Applied Life Sciences University of Massachusetts Amherst Life Science Laboratories 240 Thatcher Road Amherst, MA 01003

UMassAmherst | Core Facilities

Sensor **Integration**

Institute for Applied Life Sciences University of Massachusetts Amherst



Integration Inquiries Joseph Bardin, PhD Robert W. Jackson, PhD **Sensor Integration Codirectors** S460 Life Science Laboratories bardin@umass.edu | (413) 545-2463 jackson@ecs.umass.edu | (413) 545-1386

umass.edu/ials/sensor-integration

Facilities Inquiries Andrew Vinard Core Facilities Director S307 Life Science Laboratories avinard@umass.edu (413) 577-4582

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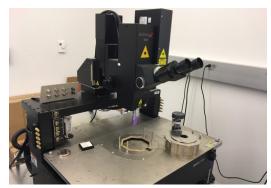
Miniaturized Electronic Systems

UMassAmherst

EQUIPMENT

Summit 11000 Probe Station with Laser Cutter

For measuring and modifying prototype integrated circuits



EZLaze3 laser cutter

- for cutting metal traces (532 nm)
- for removing passivation(355nm)

Objectives: M Plan Apo NUV 50X, 100X

Advanced Dicing Technology 7122

For precision dicing of hard material components such as silicon wafers



Work piece size: up to 200mm x 200mm Indexing: resolution/accuracy is 0.2 µm/1.5 µm Cut Depth: resolution/accuracy is 0.2 µm/2.0 µm

LPKF Protolaser U3

For prototyping of printed circuit boards



Diameter of UV laser beam 20µm Resolution of scanfield 2µm Repeatability +/- 2µm Surface structures down to 75µm Max material size 9" x 12" x 0.27"

FineTech FINEPLACER pico ma

For flip chip bonding and die attach



Placement accuracy 5 μ m Components from 0.125 mm x 0.125 mm to 100 mm x 100 mm Working area up to 450 mm x 234 mm Supports wafer/substrate sizes up to 200 mm



A significant portion of core equipment has been purchased through MLSC grant funding support.

LPKF Minicotac RS

For plating via holes in prototype printed circuit boards



Maximum size board 9" x 12" Minimum via size 0.4mm

LPKF Multi-press S

For laminating multiple layers of printed circuit boards



Laminating area 9" x 12" Up to 8 layers

Additional Equipment:

- Vector Network Analyzer: Keysight E5071c 8.5 GHz with Ecal kit
- Solder Rework Station: Weller wha3000
- Wire Bonders(2): TPT HB16 (stud bump and bump/wedge)
- DC triple power supplies (4): Keysight E3631a
- Logic Analyzer: Keysight 16806
- DC Sourcemeters(2): Keysight B2901
- Oscilloscope 1GHz: Keysight MOSX3104a
- Oscilloscope handheld: Keysight U1620a